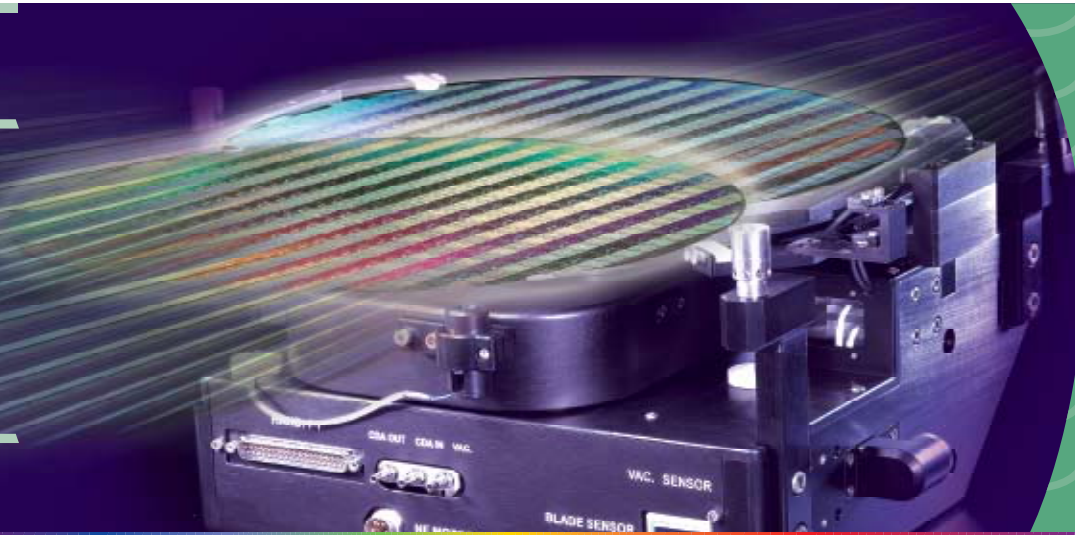
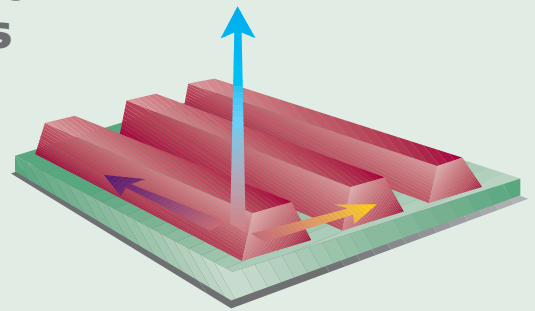


# NovaScan 3090



## DELIVERING THE CONTROL NEEDED FOR HIGH-END 65NM CMP APPLICATIONS

- Measures dielectric and conducting transparent film thickness in a non-contact process environment
- Supports thin-film measurement of front-end applications
- Comprehensive solution for array measurement in production using scatterometry techniques
- High throughput, enabling 100% pre- and post-CMP measurement
- Low cost of ownership
- APC through Closed Loop Control, with tightest possible wafer-to-wafer and within wafer control
- Various ambiances, on-line, standalone or integrated into the polisher



NovaScan 3090 delivers advanced process control for high-end applications using polarized DUV.

## APC Concept: Feed forward and feed backward

